



Attorney Docket No. 253/006 CIP.2

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Jung-Ho LEE, et al.

Art Unit: 1712

Serial No. 10/779,733

Examiner:

Filed: February 18, 2004

Confirmation No. 2084

For: METHOD OF FORMING A SILICON OXIDE  
LAYER IN A SEMICONDUCTOR  
MANUFACTURING PROCESS

**IDENTIFICATION OF RELATED APPLICATIONS**

Commissioner for Patents  
Alexandria, VA 22313-1450

Sir:

For the record, applicant has identified in the following table all U.S. patent family members relating to the captioned application.

<u>Serial No.</u>	<u>Filing Date</u>	<u>Patent No.</u>	<u>Issue Date</u>	<u>Atty. Docket #</u>	<u>Relation</u>
09/686,624	Oct. 12, 2000	6,706,646	Mar. 16, 2004	253/006 Parent	Original Parent
09/985,615	Nov. 5, 2001	6,479,405 B2	Nov. 12, 2002	253/009	1 <sup>st</sup> CIP
10/278,992	Oct. 24, 2002			253/006 DIV	1 <sup>st</sup> Div.
10/779,733	Feb. 18, 2004			253/006 CIP.2	2 <sup>nd</sup> CIP (captioned application)

Respectfully submitted,

July 12, 2004

Date

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**DEPOSIT ACCOUNT CHARGE AUTHORIZATION**

If fee payment is enclosed, this amount is believed to be correct. However, the Director is hereby authorized to charge any deficiency or credit any overpayment to Deposit Account No. 50-1645.

Any additional fee(s) necessary to effect the proper and timely filing of the above-paper may also be charged to Deposit Account No. 50-1645.